## Claims

## We claim:

- 5 1. A direct chip attach structure comprising: a support substrate having a first major surface; an electronic chip coupled to the first major surface, wherein the electronic chip includes a bond pad on an outer surface;
- a conductive stud coupled to the bond pad;
  a protective layer covering said electronic chip and a
  portion of the first major surface, wherein the protective
  layer has an opening to expose the conductive stud;
- a barrier layer formed on the conductive stud; and a solder ball coupled to the barrier layer.
  - 2. The structure of claim 1 wherein the barrier layer comprises nickel.
- 20 3. The structure of claim 2 wherein the barrier layer has a thickness of approximately 2 microns to approximately 7 microns.
- 4. The structure of claim 1 wherein the conductive 25 stud comprises gold.
  - 5. The structure of claim 1 wherein the support substrate comprises a metal lead frame having a flag.
- 30 6. The structure of claim 5 wherein the metal lead frame and flag comprise copper.

7. A method for forming an electronic package comprising the steps of:

attaching an electronic chip to a support substrate, wherein the electronic chip includes a bond pad on an outer surface;

attaching a conductive stud to the bond pad; encapsulating the electronic chip to form a subassembly having an upper surface;

forming an opening in the upper surface to expose the 10 conductive stud;

forming a barrier layer on the conductive stud; and attaching a solder bump to the barrier layer.

- 8. The method of claim 7 wherein the step of forming 15 the barrier layer includes forming a nickel barrier layer.
  - 9. The method of claim 7 wherein the step of forming the barrier layer comprises the steps of:

placing the sub-assembly in an electroless plating 20 bath; and

injecting plating solution towards the opening to form the barrier layer on the conductive stud.

- 10. The method of claim 9 further comprising the step of agitating the electroless plating bath.
  - 11. The method of claim 9 wherein the step of placing the sub-assembly includes placing the sub-assembly in an electroless nickel plating solution.

12. The method of claim 9 further comprising the step of masking the support substrate.

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- 13. The method of claim 7 wherein the step of attaching the conductive stud includes attaching a gold stud.
- 5 14. A method for forming a direct chip attach device comprising the steps of:

providing a sub-assembly comprising a lead frame, a chip attached the lead frame, a bond pad formed on an outer surface of the chip, a conductive bump attached to the bond pad, and an encapsulating layer covering the chip, wherein the encapsulating layer has an opening to expose the conductive bump;

placing the sub-assembly in an electroless plating solution; and

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injecting electroless plating solution towards the opening to form a barrier layer on the conductive bump.

- 15. The method of claim 14 further comprising the step of covering exposed portions of the lead frame with a masking layer.
  - 16. The method of claim 14 wherein the step of placing the sub-assembly includes placing the sub-assembly in an electroless nickel plating bath.

17. The method of claim 14 further comprising the step of coupling a solder bump to the barrier layer.

18. The method of claim 14 further comprising the step 30 of agitating the electroless plating solution.

19. A plating apparatus for forming an electronic device comprising:

a bath for holding a plating solution and the 5 electronic device; and

an injecting device for directing a stream of plating solution towards the electronic device.

20. The plating apparatus of claim 19 further 10 comprising an agitating device.